



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.:

10/705,814

Filing Date:

November 10, 2003

Applicants:

Shinichi Nakamura

**Group Art Unit:** 

2861

Examiner:

Nguyen, Lamson D

Title:

METHOD OF DETERMINING ABNORMALITY OF

NOZZLES IN IMAGING APPARATUS; IMAGING

APPARATUS; ELECTROOPTIC DEVICE, METHOD OF MANUFACTURING ELECTROOPTIC DEVICE; AND

**ELECTRONIC EQUIPMENT** 

Attorney Docket:

9319H-000586

Mail Stop Non-Fee Amendment Director of The United States Patent and Trademark Office P.O. Box 1450 Alexandria, Virginia 22313-1450

## **AMENDMENT AFTER ALLOWANCE RULE 1.312**

Sir:

In response to the Notice of Allowance dated March 29, 2006, please amend this application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 7 of this paper.